WHAT IS CLAIMED IS:

1. A discrete semiconductor device comprising:

die bond pads and wire bond pads arranged at specified intervals,

discrete semiconductor elements which are fastened on the back face thereof onto the die bond/pads and have electrodes electrically connected to the wire bond pads, and

a sealing resin provided on one side of the die bond pads and the wire bond pads thereby to seal the discrete semiconductor elements.

2. A discrete semiconductor device as claimed in claim 1, wherein

the die bond pads and the wire bond pads are electrically conductive metal sheets which are fastened at specified positions on the back of an insulating sheet and have aperture in the insulating sheet on the metal sheets, and

the sealing resin is provided/on one side of the die bond pads and the wire bond hads thereby to seal the discrete semiconductor element.

3. A discrete semiconductor device as claimed in claim 2, wherein

the plurality of discrete semiconductor elements are sealed with the integral sealing resin.

4. A discrete semiconductor device as claimed in claim 1, wherein

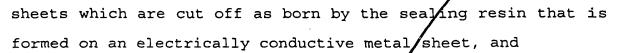
the die bond pads and the wire bond pads are the metal

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the sealing resin is provided on one side of the die bond pads and the wire bond pads thereby to fasten the die bond pads and the wire bond pads at specified intervals and seal the discrete semiconductor element.

5. A discrete semiconductor device as claimed in claim 4, wherein

the plurality of discrete semiconductor elements are sealed with the integral sealing resin.

6. A discrete semiconductor device as claimed in claim 4, wherein

the plurality of discrete semiconductor elements, having the die bond pads and or the wire bond pads in common, are sealed with the integral resin.

7. A discrete semiconductor device as claimed in claim 1, wherein

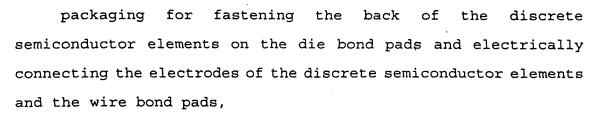
the discrete semiconductor device has electrodes on the back thereof and is electrically connected with the wire bond pads.

A method for producing a discrete semiconductor device, comprising the steps of:

forming the plurality of sets of die bond pad and wire bond pads by fastening electrically conductive metal sheets at specified positions on the back of an insulating sheet and making apertures in the insulating sheet on the metal sheets,

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sealing the plurality of the discrete semiconductor elements installed on the insulating sheet with an integral sealing resin by sealing the packaging surface of the insulating sheet with the resin, and

dividing the sealing resin into the discrete semiconductor devices by cutting off the sealing resin around the discrete semiconductor elements.

29. A method as claimed in claim 8, wherein

the step of packaging described above also include a step of fastening the back side electrode of the discrete semiconductor device onto the die bond pad to electrically connect the die bond pad and the back side electrode.

 $\mathcal{I}_{\mathcal{I}}$. A method as claimed in claim \mathscr{S} , wherein

the dividing step also be a step of cutting off the sealing resin around a plurality of discrete semiconductor elements grouped as a single body, to obtain the discrete semiconductor device wherein the plurality of discrete semiconductor elements are sealed with the integral resin.

A method for producing a discrete semiconductor device, comprising the steps of:

packaging step wherein a plurality of discrete semiconductor elements are fastened, on the back thereof, onto

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an electrically conductive metal sheet and an electrode of each discrete semiconductor element is electrically connected to a specified position of the metal sheet,

sealing the packaging surface of the metal sheet with an integral sealing resin, a cut-off step of cutting off the metal sheet by cutting therein from the back thereby to turn the metal sheet into die bond pads and wire bond pads which are arranged at intervals, and

dividing the discrete semiconductor devices by cutting off the sealing resin around the discrete semiconductor elements.

2)2. A method as claimed in claim 11, wherein

the packaging step also include a step of fastening the back electrode of the discrete semiconductor elements onto the metal sheet and electrically connecting the metal sheet and the back electrode.

4 18. A method as claimed in claim 11, wherein

the dividing step also be a step of cutting off the sealing resin around a plurality of discrete semiconductor elements grouped as a single body, to divide the discrete semiconductor devices each carrying the plurality of discrete semiconductor elements being sealed with the integral resin.

7 14. A method as claimed in claim 11, wherein

the cut-off step also be a step of cutting off the metal sheet in such a way as the die bond pads and/or the wire bond pads connected to the plurality of discrete semiconductor elements become an integral body, and

